

PCT

(30) Priority Data: 60/116,112

WORLD INTELLECTUAL PROPERTY ORGANIZATION International Bureau



INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(51) International Patent Classification 7:
H01L 51/20
A1
(11) International Publication Number: WO 00/42668
(43) International Publication Date: 20 July 2000 (20.07.00)
(21) International Application Number: PCT/US99/30612 (81) Designated States: CA, CN, JP, KR, SG, European patent (AT,

US

(22) International Filing Date: 22 December 1999 (22.12.99)

(22) International Filing Date: 22 December 1999 (22.12.99)

15 January 1999 (15.01.99)

(71) Applicant: THE DOW CHEMICAL COMPANY [US/US]; 2030 Dow Center, Midland, MI 48674 (US).

(72) Inventors: BERNIUS, Mark, T.; 401 Mayfield Lane, Midland, MI 48640 (US). WOO, Edmund, P.; 300 Mayfield Lane, Midland, MI 48640 (US).

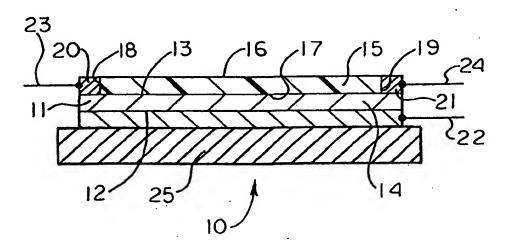
(74) Agent: ZERULL, Susan, Moeller; Intellectual Property, P.O. Box 1967, Midland, MI 48641-1967 (US).

(81) Designated States: CA, CN, IP, KR, SG, European patent (AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE).

Published

With international search report.

(54) Title: SEMICONDUCTING POLYMER FIELD EFFECT TRANSISTOR



(57) Abstract

A field effect transistor is made of five parts. The first part is an insulator layer, the insulator layer being an electrical insulator such as silica, the insulator layer having a first side and a second side. The second part is a gate, the gate being an electrical conductor such as silver, the gate being positioned on the first side of the insulator layer. The third part is a semiconductor layer, the semiconductor layer including a polymer, at least ten weight percent of the monomer units of the polymer being a 9-substituted fluorene unit and/or a 9,9-substituted fluorene unit, the semiconductor layer having a first side, a second side, a first end and a second end, the second side of the semiconductor layer being on the second side of the insulator layer. The fourth part is a source, the source being an electrical contact with the first end of the semiconductor layer. The fifth part is a drain, the drain being an electrical conductor such as silver, the drain being in electrical contact with the second end of the semiconductor layer. A negative voltage bias applied to the gate causes the formation of a conduction channel in the semiconductor layer from the source to the drain. On the other hand, a positive bias applied to the gate causes the formation of an electron conducting channel in the semiconductor layer.